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## **BIB DATA SHEET**

## **CONFIRMATION NO. 5607**

10/593,830 09/22/2006 382 2829 296431US2PCT  RULE  APPLICANTS  Hisao Igarashi, Chuo-Ku, JAPAN;  Katsumi Sato, Chuo-Ku, JAPAN;  Kazuo Inoue, Chuo-Ku, JAPAN;  ** CONTINUING DATA **********************************	SERIAL NUM	IBER FILING or 371(c)		CLASS GI		GRO	GROUP ART UNIT		ATTORNEY DOCKET NO.			
APPLICANTS  Hisao Igarashi, Chuo-Ku, JAPAN; Katsumi Sato, Chuo-Ku, JAPAN; Kazuo Inoue, Chuo-Ku, JAPAN; Kazuo Inoue, Chuo-Ku, JAPAN; This application is a 371 of PCT/JP05/06108 03/30/2005  **FOREIGN APPLICATIONS  JAPAN 2004-102948 03/31/2004  **IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 04/26/2007  Foreign Priority claimed	10/593,83	10/593,830				382	2829					
Hisao Igarashi, Chuo-Ku, JAPAN; Katsumi Sato, Chuo-Ku, JAPAN; This application is a 371 of PCT/JP05/06108 03/30/2005  **FOREIGN APPLICATIONS *** JAPAN 2004-102948 03/31/2004  **IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 04/26/2007  Foreign Priority claimed			RULE	<b>=</b>								
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35 USC 119(a-d) conditions met	** IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 04/26/2007											
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OBLON, SPIVAK, MCCLELLAND MAIER & NEUSTADT, P.C.  1940 DUKE STREET ALEXANDRIA, VA 22314 UNITED STATES  TITLE  Probe apparatus,wafer inspecting apparatus provided with the probe apparatus and wafer inspecting method  FEES: Authority has been given in Paper No to charge/credit DEPOSIT ACCOUNT No for following:    All Fees     1.16 Fees (Filing)     1.17 Fees (Processing Ext. of time)     1.18 Fees (Issue)     Other	Verified and /MINH NHUT TANG/ MT				ance		DDA					
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FILING FEE RECEIVED 1260  Probe apparatus,wafer inspecting apparatus provided with the probe apparatus and wafer inspecting method	1940 DÚI ALEXANI	KE STF DRIA, V	RÉET /A 22314	ND MAIE	ER & N	EUSTADT, P.C.						
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